



BOX AF
RESPONSE UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE
EXAMINER GROUP 2125

8/B
~~# 5~~
45-03
E 1666

00862.022168

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Seiji TAKEUCHI et al.

Application No.: 09/819,670

Filed: March 29, 2001

For: STOCKER, EXPOSURE APPARATUS,
DEVICE MANUFACTURING METHOD,
SEMICONDUCTOR MANUFACTURING
FACTORY, AND EXPOSURE APPARATUS:
MAINTENANCE METHOD

)
: Examiner: A. Kosowski
)
: Group Art Unit: 2125

RECEIVED

AUG 28 2003

August 25, 2003 Technology Center 2100
(Monday)

Mail Stop AF

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL ACTION

Sir:

In response to the Office Action dated May 23, 2003, the time for response being extended from Saturday, August 23, 2003 to August 25, 2003, please amend the above identified application as follows pursuant to 37 C.F.R. § 1.116: